

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Tomio ONO, et al.

SERIAL NO: NEW APPLICATION

GAU:

FILED: HEREWITH

EXAMINER:

FOR: MICROSWITCH AND METHOD OF MANUFACTURING THE SAME

**INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97**

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

**REFERENCES**

The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.

A check is attached in the amount required under 37 CFR §1.17(p).

**RELATED CASES**

Attached is a list of applicant's pending application(s) or issued patent(s) which may be related to the present application. A copy of the patent(s), together with a copy of the claims and drawings of the pending application(s) is attached along with PTO 1449.

A check is attached in the amount required under 37 CFR §1.17(p).

**CERTIFICATION**

Each item of information contained in this information disclosure statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

**DEPOSIT ACCOUNT**

Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment form is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 242814US2SRD		SERIAL NO. NEW APPLICATION	
				APPLICANT Tomio ONO, et al.			
		LIST OF REFERENCES CITED BY APPLICANT		FILING DATE HEREWITH		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
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FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION		
					YES	NO	
	AQ						
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
•	AW	Paul M. ZAVRACKY, et al., "Micromechanical Switches Fabricated Using Nickel Surface Micromachining", JOURNAL OF MICROELECTROMECHANICAL SYSTEMS, Vol. 6, No. 1, March 1997, pgs. 3-9					
	AX	S. ERTL, et al., "Surface Micromachined Diamond Microswitch", DIAMOND AND RELATED MATERIALS, Vol. 9, 2000, pgs 970-974					
	AY	M. ADAMSCHIK, et al., "Diamond Microwave Micro Relay", DIAMOND AND RELATED MATERIALS, Vol. 11, 2002, pgs. 672-676					
	AZ				<input type="checkbox"/> Additional References sheet(s) attached		
Examiner				Date Considered			
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

DOCKET NO: 242814US2SRD

Sheet 1 of 1

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**STATEMENT OF RELEVANCY**

**Reference AW on Form PTO- 1449:**

This reference shows typical micromachined microswitch structure (Fig. 1.) and fabrication process (Fig. 2.).

**Reference AX on Form PTO- 1449:**

This reference shows diamond microswitch structure (Fig. 1.) and fabrication process (Fig. 2.). In this reference, it was reported that no sticking was observed.

**Reference AY on Form PTO- 1449:**

This reference shows diamond microswitch structure to reduce contact resistance (Fig. 2.). But diamond contact is mechanically weak and reduction of contact resistance is insufficient.